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DATE: October 4, 2004
FILE NO: AMAT/3032.C7/DSM/LOW K/JW
TO: Examiner: Thao P. Le
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COMPANY: USPTO
FROM: Keith M. Tackett
PAGE(S) with cover: 8
ORIGINAL TO FOLLOW? ☐ YES ☒ NO

RESPONSE TO FINAL OFFICE ACTION DATED AUGUST 6, 2004

TITLE: Plasma Processes for Depositing Low Dielectric Constant Films
U.S. SERIAL NO.: 10/647,959
FILING DATE: August 26, 2003
INVENTOR: Cheung, et al.
EXAMINER: Thao P. Le
GROUP ART UNIT: 2818
CONFIRMATION NO.: 5142

CONFIDENTIALITY NOTE

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